

REMARKS

This is in full and timely response to the final Office Action mailed May 22, 2003, submitted concurrently with a Petition for Extension of Time to within the second extended month.

By this Amendment, claims 1, 2, 8, 9, 12, and 15-17 were amended, claims 3-6, 1-11 and 13-14 were canceled, and claims 18-27 were added. Claims 1, 2, 8, 9, 12, and 15-17 were amended for clarity and better idiomatic English. Support for these amendments can be found variously throughout the specification, for example, at least original claims 1, 2, 8, 9, 12, and 15-17. Support for new claim 18 can be found variously throughout the specification, for example, at page 9, line 11 to page 10, line 12 and Fig. 5. Support for new claims 19-23 can be found variously throughout the specification, for example, at least in original claims 3-6, at page 9, line 11 to page 10, line 12 and Fig. 5. Support for new claim 24 can be found variously throughout the specification, for example, at least in original claims 10. Support for new claim 25 can be found variously throughout the specification, for example, at least in original claims 11. Support for new claim 26 can be found variously throughout the specification, for example, at least in original claims 13. Support for new claim 27 can be found variously throughout the specification, for example, at least in original claims 14. No new matter was added. Claims 1-2, 7-9, 12 and 15-27 are pending in this application, with claim 1 being independent. By this Amendment, Applicant believes that all pending claims are in condition for allowance. Reexamination and reconsideration in light of the above amendments and the following remarks is respectfully requested.

Rejections under 35 U.S.C. §102

Claims 1-5 and 7-8 are rejected under 35 U.S.C. 102(b) as anticipated by U.S. Patent No. 4,786,867 to Yamatsu. Applicants respectfully traverse this rejection. By this Amendment, claims 3-6 were canceled, mooting this portion of the rejection.

Claim 1 recites a substrate processing system comprising: first and second processing units adapted to process a substrate by a first treatment and a second treatment, respectively; first image pickup means adapted to pick-up an image of a member of the processing units or the substrate being placed in the processing units; a transfer apparatus adapted to convey the substrate between the processing units and including a substrate carrying arm adapted to hold the substrate when the

transfer apparatus conveys the substrate; wherein the first image pickup means is mounted to the transfer apparatus such that the first image pickup means moves together with the substrate carrying arm at least when the substrate carrying arm is moving in a first direction.

In the claimed invention, the first image pickup means (for example, CCD camera 61) is mounted to the transfer apparatus (for example, first image pickup means is attached to the wafer carrying arm 183 or support member 59) such that the first image pickup means moves together with the substrate carrying arm at least when the substrate carrying arm is moving in a first direction (for example, vertical direction). See also the specification at page 23, line 23 to page 24, lines 6.

Yamatsu '867 discloses a wafer prober for use in the examination of electric characteristics of semiconductor chips formed on a semiconductor wafer. However, units 5 (calculator), 12 (driving motor), 13 (detector) and 14 (controller) of Yamatsu '867 do not process a substrate by a predetermined treatment. Additionally, the transfer apparatus 3 (X-Y table) of Yamatsu '867 does not transfer the substrate between the processing units each configured to process a substrate by a predetermined treatment. Still further, the first image pickup means 9 (image recognizing device) of Yamatsu '867 is not mounted to the transfer apparatus such that the first image pickup means moves together with the substrate carrying arm. The image recognizing device 9 is fixedly arranged at a position. See, for example, column 3, lines 38-43.

A document can only anticipate a claim if the document discloses, explicitly or implicitly, each and every feature recited in the claim. Verdegall Bros. v. Union Oil Co. of Calif., 814 F.2d 628, 631, 2 USPQ2d 1051, 1053 (Fed. Cir. 1987). Since Yamatsu '867 fails to disclose, either explicitly or implicitly, teach or suggest at least the above-noted features recited in independent claim 1, Yamatsu '867 cannot anticipate the claim. At least in view of the foregoing, claim 1 is allowable, and the rejection should be reconsidered and withdrawn.

Claims 2, 7 and 8, being dependent upon claim 1, are also allowable for the reasons above. Moreover, these claim are further distinguished by the materials recited therein, particularly within the claimed combination. Accordingly, the §102 rejection should be withdrawn.

Rejections under 35 U.S.C. §103

Claims 6 and 9-17 are rejected under 35 U.S.C. 103(a) as being unpatentable over U.S. Patent No. 4,786,867 to Yamatsu in view of U.S. Patent No. 5,815,594 to Tanaka. Applicants respectfully traverse this rejection. Claims 6, 10-11 and 13-14 were canceled, mooted this portion of the rejection.

In Tanaka '594, the wafer chuck 5 and the XY-stage 6 are not equivalent of the transfer apparatus of the present invention. This is because they never transfers a substrate between the first processing unit adapted to process the substrate by a first treatment and the second processing unit adapted to process the substrate by a second treatment. In other respects, Tanaka is completely different from the claimed invention of claim 1. Accordingly, as all of the elements of the claims are not shown, Tanaka '594 does not make up for the deficiencies of Yamatsu '867, and a prima facie case of obviousness does not exist.

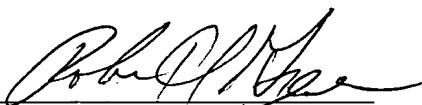
Still further, claims 9, 12 and 15-17, being dependent upon claim 1, are also allowable for the reasons above. Moreover, these claims are further distinguished by the materials recited therein, particularly within the claimed combination. Accordingly, the §103 rejection should be withdrawn.

CONCLUSION

For the foregoing reasons, all the claims now pending in the present application are believed to be clearly patentable over the prior art of record. Accordingly, favorable reconsideration of the claims in light of the above remarks is courteously solicited. If the Examiner has any comments or suggestions that could place this application in even better form, the Examiner is requested to telephone the undersigned attorney at the below-listed number.

Dated: October 22, 2003

Respectfully submitted,

By 

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